

ABSTRACT OF THE DISCLOSURE

There is provided a piezoelectric/electrostrictive film type device comprising: a substrate formed of a ceramic, at least one piezoelectric/electrostrictive portion formed of a piezoelectric/electrostrictive porcelain composition on the substrate, and at least one pair of electrodes on the substrate, electrically connected to the piezoelectric/electrostrictive portion and including a positive electrode and a negative electrode. The piezoelectric/electrostrictive porcelain composition contains a  $\text{PbMg}_{1/3}\text{Nb}_{2/3}\text{O}_3$ - $\text{PbZrO}_3$ - $\text{PbTiO}_3$  ternary solid solution system composition as a major component, and contains 0.05 to 3.0wt% of NiO, and contains 2.0 to 22.0 mol% of Si with respect to the total number of moles of Mg and Ni. The piezoelectric/electrostrictive portion is solidly attached onto the substrate directly or via the positive electrode or the negative electrode.